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2814

MEMC 98-3052 (2512.2)
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

5 Elec.
4/24/03
amr

Application of Robert J. Falster

Art Unit 2814

Serial No. 10/038,084

Filed January 03, 2002

Confirmation No. 7363

For SILICON ON INSULATOR STRUCTURE HAVING A LOW DEFECT DENSITY
DEVICE LAYER AND A PROCESS FOR THE PREPARATION THEREOF

Examiner Anh D. Mai

April 17, 2003

RESPONSE TO RESTRICTION REQUIREMENT

TO THE ASSISTANT COMMISSIONER FOR PATENTS,

SIR:

In response to the restriction requirement dated March 6, 2003, Applicant elects examination of claims 47-51 (Group II).

Applicant therefore withdraws from consideration, without prejudice to their patentability, claims 4-46 (Group I). Applicant also expressly reserves the right to file one or more divisional applications directed to these claims in the future.

Respectfully submitted,

Richard A. Schuth, Reg. No. 47,929
SENNIGER, POWERS, LEAVITT & ROEDEL
One Metropolitan Square, 16th Floor
St. Louis, Missouri 63102
(314) 231-5400

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